NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

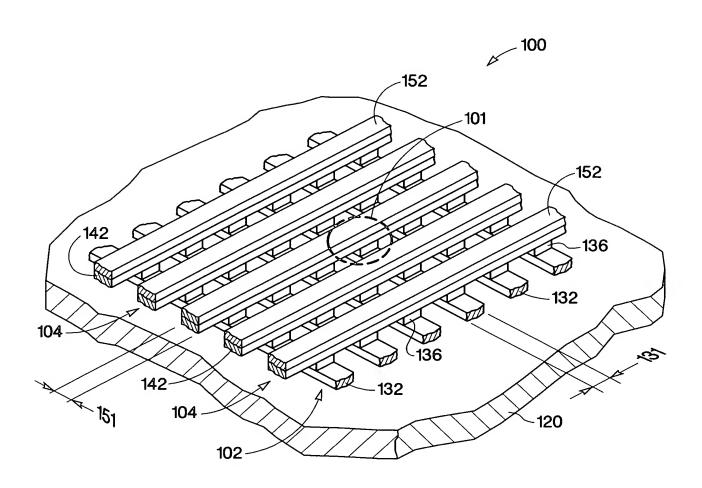


Fig. 1a

NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

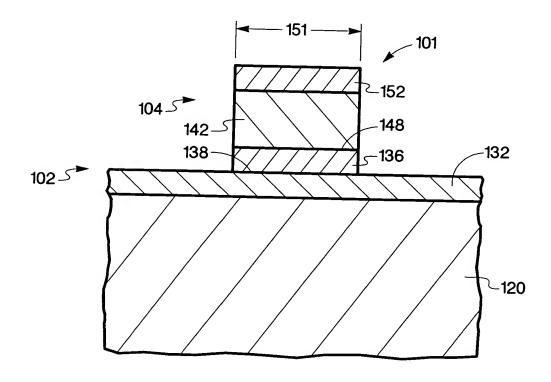


Fig. 1b

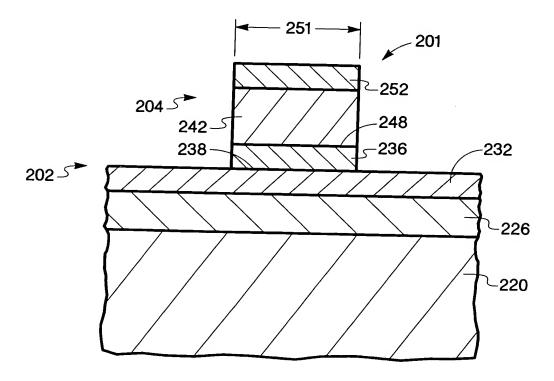


Fig. 2

NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

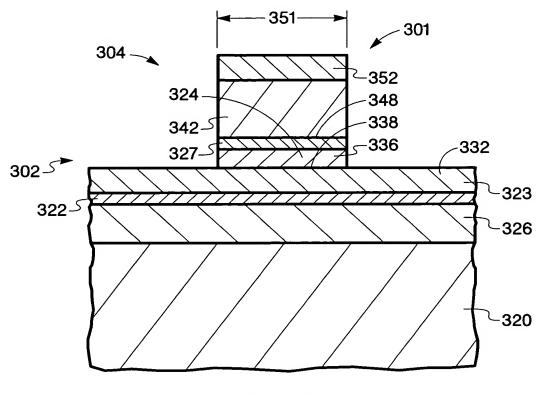


Fig. 3

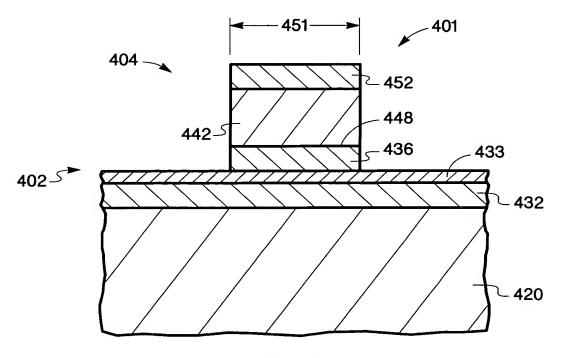


Fig. 4

NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

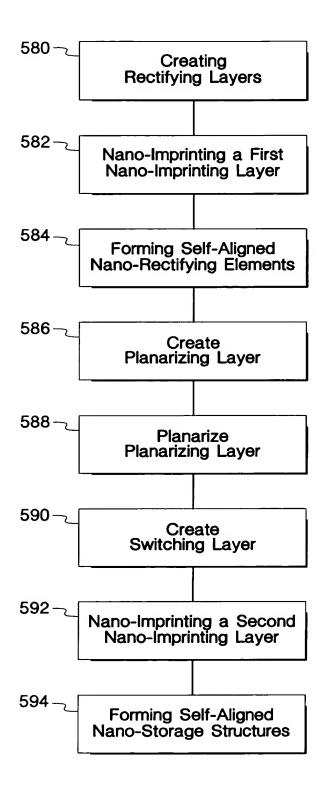
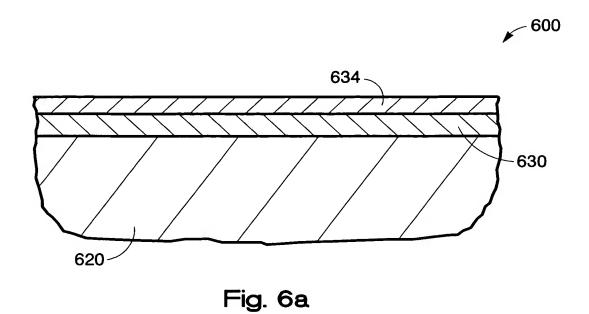


Fig. 5

NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.



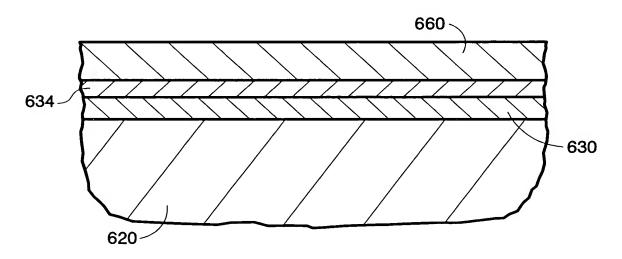


Fig. 6b

NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

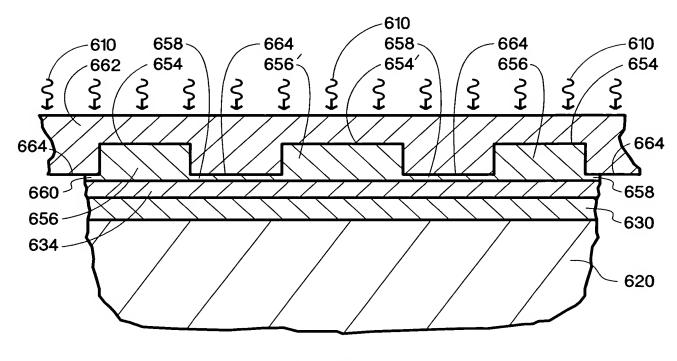


Fig. 6c

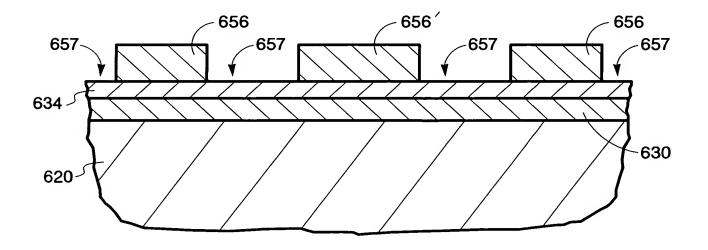
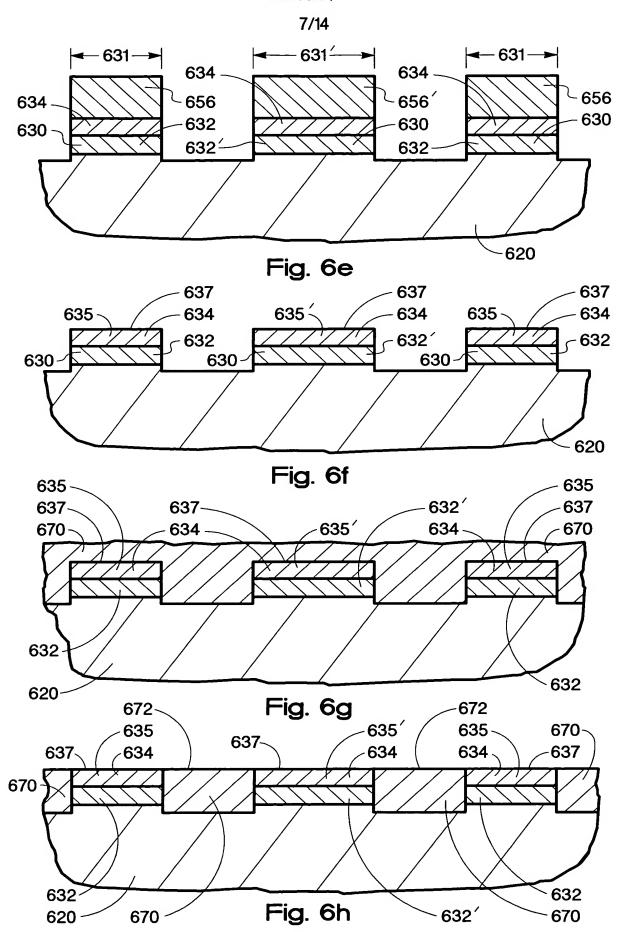


Fig. 6d

NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.



NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

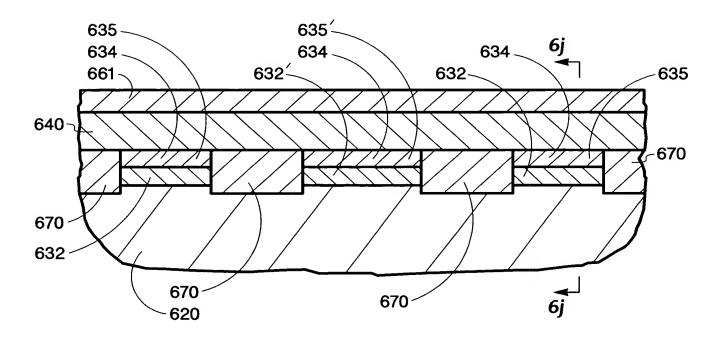


Fig. 6i

NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

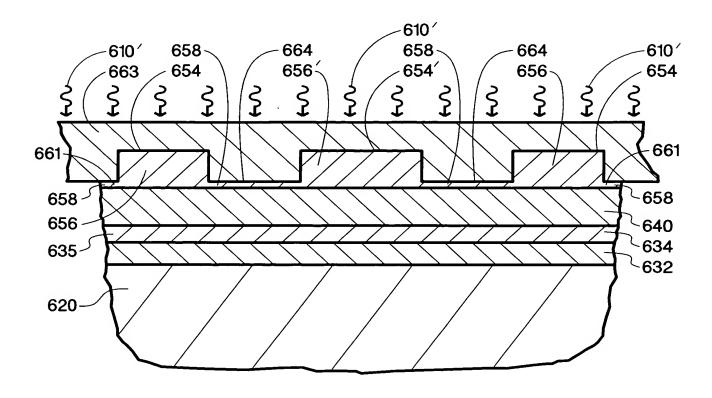


Fig. 6j

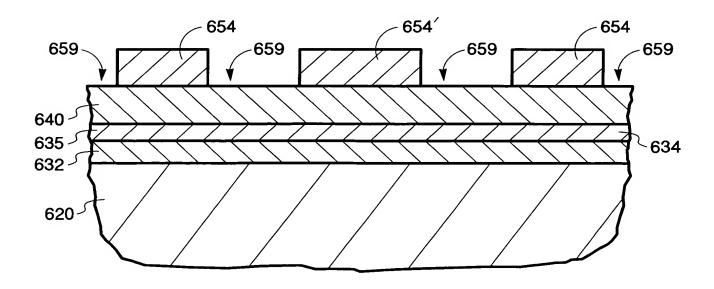
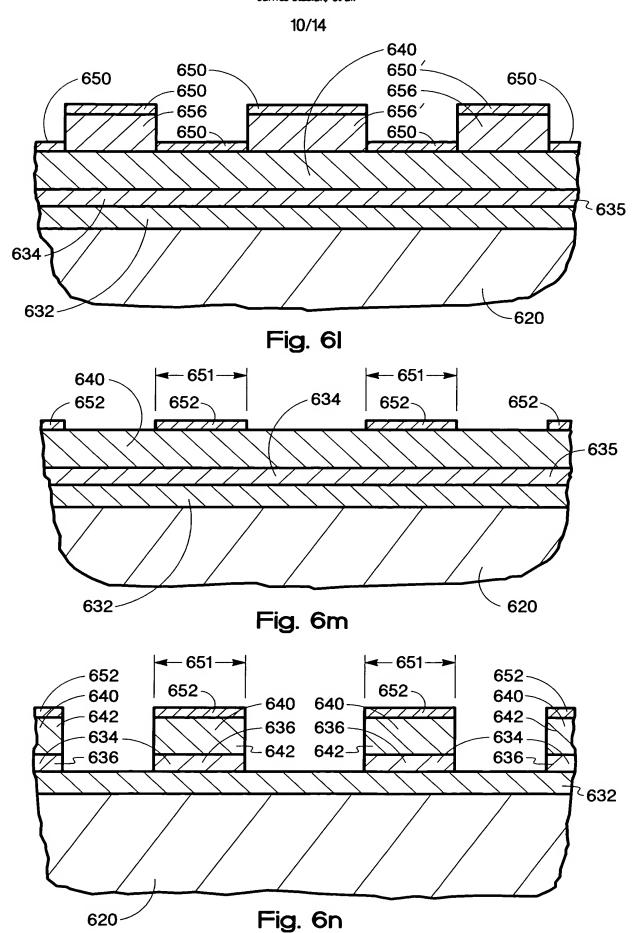


Fig. 6k

NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.



NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

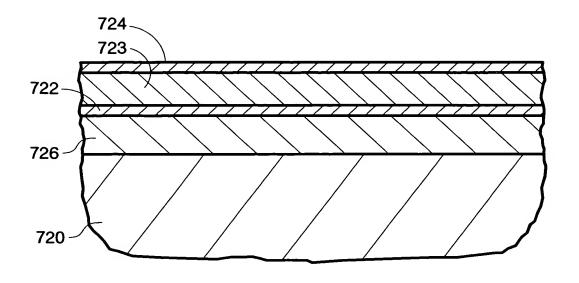
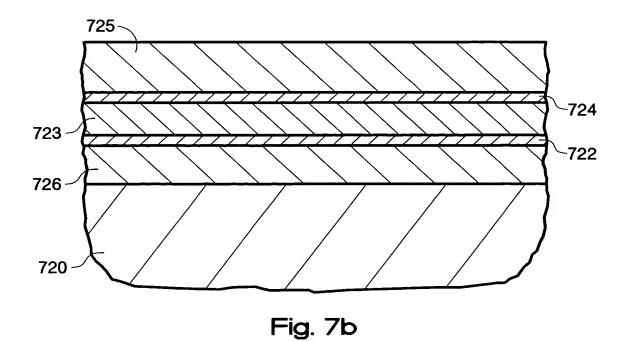


Fig. 7a



NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

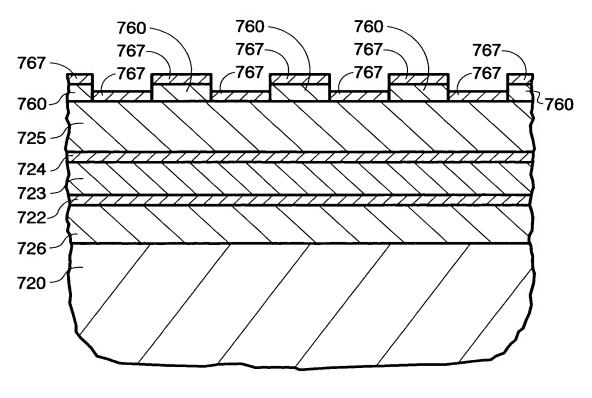


Fig. 7c

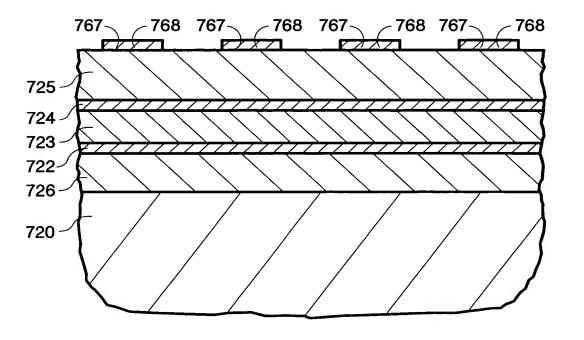


Fig. 7d

NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

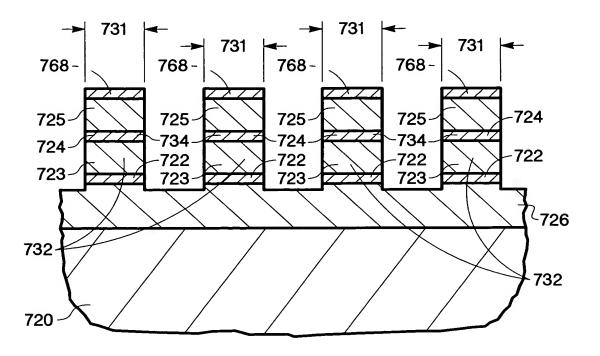
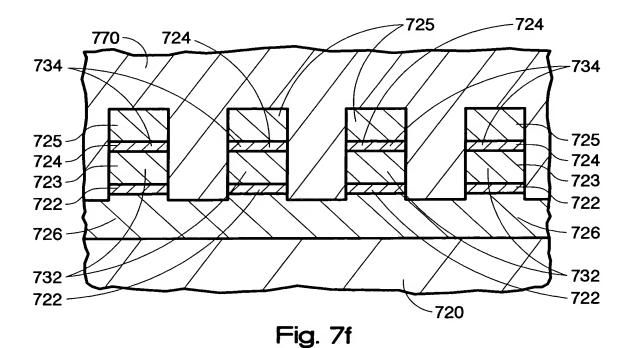


Fig. 7e



NANOMETER-SCALE MEMORY DEVICE UTILIZING SELF-ALIGNED RECTIFYING ELEMENTS AND METHOD OF MAKING

James Stasiak, et al.

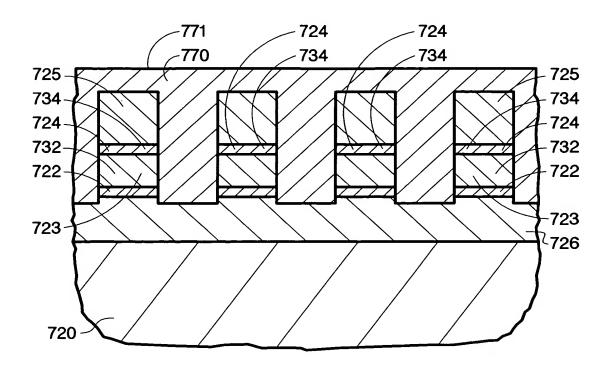


Fig. 7g

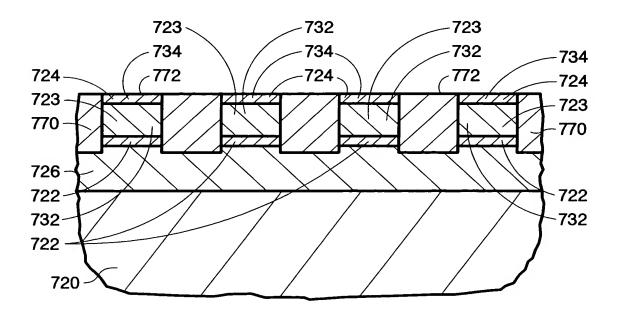


Fig. 7h